



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

RECEIVED AF
JAN 26 2004
TC 1700

re the Application of: HATTORI, Kazuhiro

Serial No.: 09/816,784

Group Art Unit: 1765

Filed: March 26, 2001

Examiner: Lan Vinh

P.T.O. Confirmation No.: 5542

For: DRY ETCHING METHOD, MICROFABRICATION PROCESS AND DRY
ETCHING MASK

OK to enter
LV
2/5/2004

RESPONSE UNDER 37 CFR §1.116

- EXPEDITED RESPONSE -
GROUP ART UNIT 1765

MAILSTOP AF

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

January 22, 2004

Sir:

In response to the Office Action dated **October 22, 2003**, please amend the above-identified application as follows: